



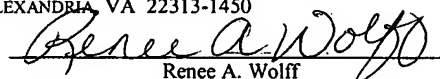
IFW

PATENT APPLICATION
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Oikari et al.	Examiner:	Carrillo, Bibi Sharidan
Serial No.:	10/613,931	Group Art Unit:	1746
Filed:	July 3, 2003		
For:	WAFER PROCESSING USING GASEOUS ANTISTATIC AGENT DURING DRYING PHASE TO CONTROL CHARGE BUILD- UP	Docket No.	FSI0111/US

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I CERTIFY THAT ON NOVEMBER 17, 2004, THIS PAPER IS BEING
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Renee A. Wolff

AMENDMENT

Dear Sir:

In response to the outstanding Official Action mailed August 17, 2004 please
amend the above-identified application as presented below.